IN THE UNITED STATES PATENT AND TRADEMARK OFFICE AS DESIGNATED/ELECTED OFFICE

| Applicant: Philippe Cormont, et al. |) | Title: Method and Device for Lithography by Extreme Ultraviolet Radiation |
|-------------------------------------|---|---|
| Serial No.: To be assigned |) | |
| Intl. Appl. No.: PCT/FR2004/002226 |) | Group Art Unit: To be assigned |
| Intl Filing Date: 01 September 2004 |) | Examiner: To be assigned |
| mit Fining Date. 01 September 2004 |) | Filed: Herewith |

PRELIMINARY AMENDMENT ACCOMPANYING FILING OF NATIONAL STAGE APPLICATION UNDER 35 U.S.C. 371

Mail Stop PCT Commissioner for Patents P.O. Box 1450 Alexandria, Virginia 22313-1450

Sir:

Prior to examination, please amend the accompanying application as follows:

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 3 of this paper.

Remarks/Arguments begin on page 11 of this paper.